

FEI Strata 400S

SN - D1074

Vintage – 2006

Electron Column - Sirion

Ion Column - Sidewinder

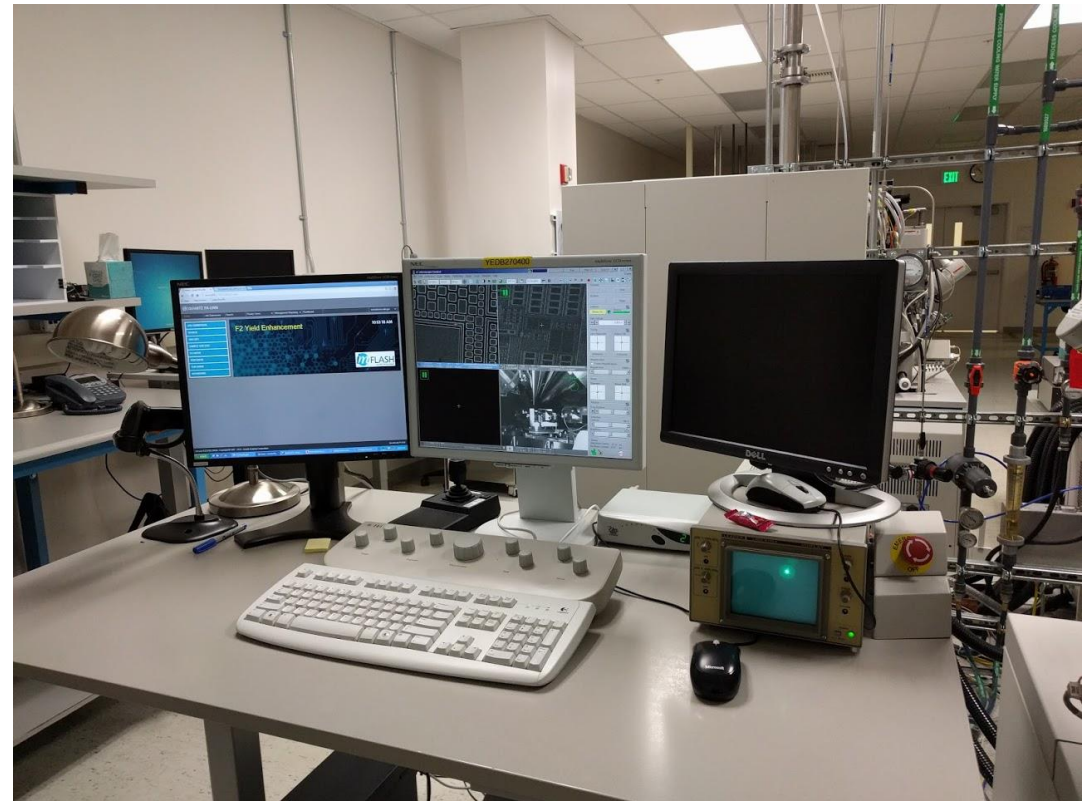
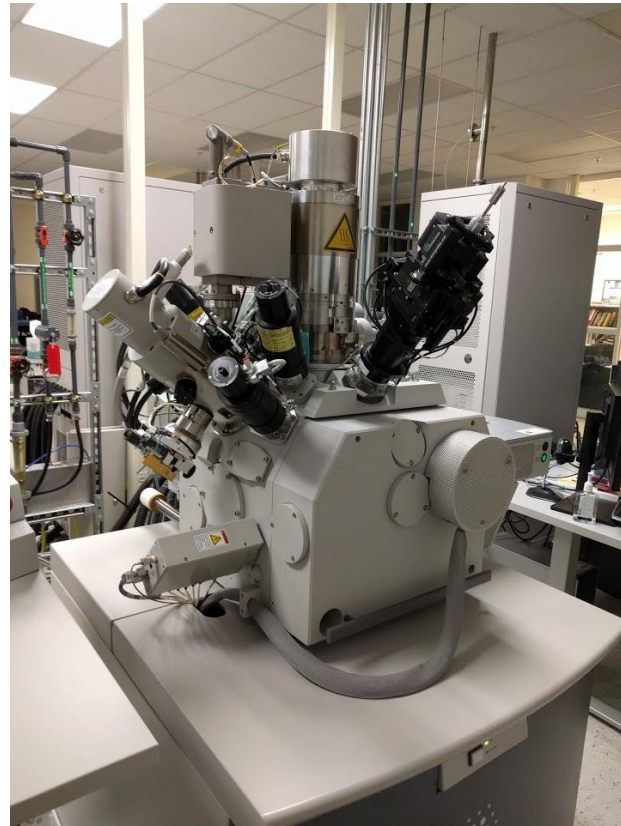
- **FEI STRATA 400S Spec**
- The “S” from 400S designates the STEM option which includes:
 - Flip stage for S/TEM prep
 - Omniprobe for S/TEM sample lift out
 - And STEM detector for STEM imaging.
- It also has the platinum deposition/enhanced etch/Insulator enhanced and the Knights (now Camelot) CAD Navigation keys.

Specifications

Electron source	Schottky thermal field emitter, over 1 year lifetime
Ion source	Gallium liquid metal, 1000 hours guaranteed
Beam voltage	200 V - 30 kV SEM, 2 kV - 30 kV FIB
Image resolution	< 0.8 nm achievable SEM-STEM mode
EDX resolution	< 30 nm on thinned samples
Sample types	Wafer pieces, packaged parts, TEM half-grids
Max sample size	75 mm diameter, loadlock compatible
Flipstage	Removable Row Holder holds up to six TEM grids Total tilt range > 150 degrees (excluding tilt of main DualBeam stage) External load base for loading/unloading grids from row holder In-situ section extraction system
SEM-STEM detector	Multi-region: bright field, dark field, 12 high-angle dark field segments
User interface	Windows 2000® GUI with integrated SEM, FIB, GIS, imaging and patterning Simultaneous patterning and imaging mode

Key Options

Gas chemistry	Range of proprietary deposition and etch chemistries
Automation software	AutoFIB™, AutoTEM™, AutoSlice&View™
Hardware	EDX Analysis



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Product version	2.0.6 REL
Build date	05-15-2007
Build number	1189 [Release]
D-Number	D1073
Machine type	Strata DB-STEP